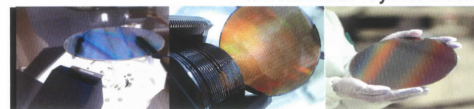


The Development and the commercialization of the Mask Aligner for wafer
Midas System will continue to grow along with the value creation for our customers.



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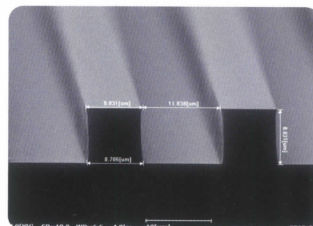
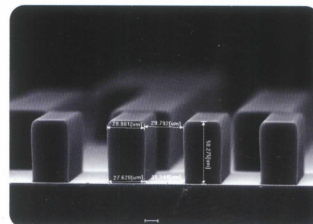
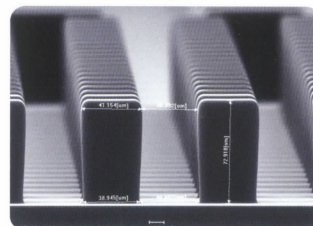
MDA-400M



The MDA-400M is widely used for MEMS, LED and semiconductor industry. This machine can make a higher performance of Alignment accuracy and resolution. It is ideal, economical unit for University and Research center.



SEM Image



ITEM	SPECIFICATIONS
Substrate Size	Up to 6 inch
UV Lamp Power	350W
Resolution	0.8 μ m
Alignment Accuracy	1 μ m
Lamp Uniformity	$\leq 3\%$ (4")
Uniform Beam Size	6.25" \times 6.25"
365nm Beam Intensity	20~25mW/cm ²
Exposure Time	0.1 ~ 999.9 sec
Process mode	Vacuum, Hard, Soft and Proximity
Option	BSA(IR type), UV-NIL, UV intensity meter, Anti-Vibration table
Dimension	1,050 \times 1,088 \times 1,561mm (Anti-Vibration Table Inclusion)



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